

UCF MATERIALS CHARACTERIZATION FACILITY
OTHER UNIVERSITY AND LEARNING INSTITUTIONS FEE SCHEDULE
2024-2025

<u>Equipment</u>	<u>Hourly Rate</u>
Scanning Electron Microscopy (SEM)	
Jeol JSM-6480	60
Zeiss Ultra-55	97
Transmission Electron Microscopy (TEM)	
Jeol JEM-1-11	60
Tecnai F30	119
Focused Ion Beam (FIB)	
FEI 200 TEM	89
Zeiss FIB Crossbeam	119
X-Ray Diffraction (XRD)	
XRD -- GN (Panalytical)	75
XRD -- TF (Panalytical)	89
XRD -- EC (Panalytical)	97
Secondary Ion Mass Spectrometry (SIMS)	
Cameca IMS-3F	89
PHI Adept	89
Miscellaneous	
XPS Escalab 250Xi	97
Sputter Coater (Quoram)	75
X-Ray Fluorescence Spectrometer (XRF) (Panalytical)	27
Other Instruments	
Critical Point Dryer	45
Diamond Wafering	45
Dimple Grinder	45
PECS Gatan (Coating System)	45
Ion Milling	45
Ultra Microtom (Leica)	45
Leica Trimmer	45
Metal Polisher Allied	45
Plasma Cleaner	45
Confocal Laser Scanning Microscope	45
Metallurgical Microscope	45
MicroRaman Spectroscopy	45
Profilometer	45
Reichert Optical Microscope	45